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**Discrete semiconductor devices and integrated circuits - Optoelectronic devices -  
Measuring methods (IEC 60747-5-3:1997)**

Discrete semiconductor devices and integrated circuits -- Part 5-3: Optoelectronic  
devices - Measuring methods

Einzel-Halbleiterbauelemente und integrierte Schaltungen -- Teil 5-3: Optoelektrische  
Bauelemente - Messverfahren

Dispositifs discrets à semiconducteurs et circuits intégrés -- Partie 5-3: Dispositifs  
optoélectroniques - Méthodes de mesure

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**Ta slovenski standard je istoveten z: EN 60747-5-3:2001**

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**ICS:**

31.080.01	Polprevodniški elementi (naprave) na splošno	Semiconductor devices in general
31.200	Integrirana vezja, mikroelektronika	Integrated circuits. Microelectronics
31.260	Optoelektronika, laserska oprema	Optoelectronics. Laser equipment

**SIST EN 60747-5-3:2002****en**

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EUROPEAN STANDARD

**EN 60747-5-3**

NORME EUROPÉENNE

EUROPÄISCHE NORM

July 2001

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English version

**Discrete semiconductor devices and integrated circuits**  
**Part 5-3: Optoelectronic devices -**  
**Measuring methods**  
(IEC 60747-5-3:1997)

Dispositifs discrets à semiconducteurs et  
circuits intégrés  
Partie 5-3: Dispositifs optoélectroniques -  
Méthodes de mesure  
(CEI 60747-5-3:1997)

Einzel-Halbleiterbauelemente und  
integrierte Schaltungen  
Teil 5-3: Optoelektronische Bauelemente -  
Meßverfahren  
(IEC 60747-5-3:1997)

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Up-to-date lists and bibliographical references concerning such national standards may be obtained on application to the Central Secretariat or to any CENELEC member.

This European Standard exists in three official versions (English, French, German). A version in any other language made by translation under the responsibility of a CENELEC member into its own language and notified to the Central Secretariat has the same status as the official versions.

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**CENELEC**

European Committee for Electrotechnical Standardization  
Comité Européen de Normalisation Electrotechnique  
Europäisches Komitee für Elektrotechnische Normung

**Central Secretariat: rue de Stassart 35, B - 1050 Brussels**

## Foreword

The text of the International Standard IEC 60747-5-3:1997, prepared by SC 47C, Flat panel display devices, of IEC TC 47, Semiconductor devices, was submitted to the Unique Acceptance Procedure and was approved by CENELEC as EN 60747-5-3 on 2000-12-01 without any modification.

This standard should be read jointly with IEC 60747-1, EN 62007-1 and EN 62007-2.

The following dates were fixed:

- latest date by which the EN has to be implemented at national level by publication of an identical national standard or by endorsement (dop) 2002-01-01
- latest date by which the national standards conflicting with the EN have to be withdrawn (dow) 2004-01-01

Annexes designated "normative" are part of the body of the standard.  
Annexes designated "informative" are given for information only.  
In this standard, annex ZA is normative and annex A is informative.  
Annex ZA has been added by CENELEC.

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## iTeh STANDARD PREVIEW Endorsement notice (standards.iteh.ai)

The text of the International Standard IEC 60747-5-3:1997 was approved by CENELEC as a European Standard without any modification.

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**Annex ZA**  
(normative)

**Normative references to international publications  
with their corresponding European publications**

This European Standard incorporates by dated or undated reference, provisions from other publications. These normative references are cited at the appropriate places in the text and the publications are listed hereafter. For dated references, subsequent amendments to or revisions of any of these publications apply to this European Standard only when incorporated in it by amendment or revision. For undated references the latest edition of the publication referred to applies (including amendments).

NOTE When an international publication has been modified by common modifications, indicated by (mod), the relevant EN/HD applies.

<u>Publication</u>	<u>Year</u>	<u>Title</u>	<u>EN/HD</u>	<u>Year</u>
IEC 60068-1	1988	Environmental testing Part 1: General and guidance	EN 60068-1 <sup>1)</sup>	1994
IEC 60270	1981	Partial discharge measurements	-	-

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1) EN 60068-1 includes Corrigendum October 1988 + A1:1992 to IEC 60068-1:1988.

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**Dispositifs discrets à semiconducteurs  
et circuits intégrés –**

**Partie 5-3:  
Dispositifs optoélectroniques –  
Méthodes de mesure**

**(standards.iteh.ai)**

**Discrete semiconductor devices  
and integrated circuits –**

**Part 5-3:  
Optoelectronic devices –  
Measuring methods**

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Commission Electrotechnique Internationale  
International Electrotechnical Commission  
Международная Электротехническая Комиссия

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For price, see current catalogue

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## INTERNATIONAL ELECTROTECHNICAL COMMISSION

**DISCRETE SEMICONDUCTOR DEVICES  
AND INTEGRATED CIRCUITS –****Part 5-3: Optoelectronic devices –  
Measuring methods**

## FOREWORD

- 1) The IEC (International Electrotechnical Commission) is a worldwide organization for standardization comprising all national electrotechnical committees (IEC National Committees). The object of the IEC is to promote international co-operation on all questions concerning standardization in the electrical and electronic fields. To this end and in addition to other activities, the IEC publishes International Standards. Their preparation is entrusted to technical committees; any IEC National Committee interested in the subject dealt with may participate in this preparatory work. International, governmental and non-governmental organizations liaising with the IEC also participate in this preparation. The IEC collaborates closely with the International Organization for Standardization (ISO) in accordance with conditions determined by agreement between the two organizations.
- 2) The formal decisions or agreements of the IEC on technical matters express, as nearly as possible, an international consensus of opinion on the relevant subjects since each technical committee has representation from all interested National Committees.
- 3) The documents produced have the form of recommendations for international use and are published in the form of standards, technical reports or guides and they are accepted by the National Committees in that sense.
- 4) In order to promote international unification, IEC National Committees undertake to apply IEC International Standards transparently to the maximum extent possible in their national and regional standards. Any divergence between the IEC Standard and the corresponding national or regional standard shall be clearly indicated in the latter.  
*SIST EN 60747-5-3:2002*
- 5) The IEC provides no marking procedure to indicate its approval and cannot be rendered responsible for any equipment declared to be in conformity with one of its standards.  
*95544850a/1131-01/60747-5-3-2002*
- 6) Attention is drawn to the possibility that some of the elements of this International Standard may be the subject of patent rights. The IEC shall not be held responsible for identifying any or all such patent rights.

International Standard IEC 60747-5-3 has been prepared by subcommittee 47C: Optoelectronic, display and imaging devices, of IEC technical committee 47: Semiconductor devices.

This first edition replaces partially the second edition of IEC 60747-5 (1992) and constitutes a technical revision (see also annex A: Cross references index).

It should be read jointly with IEC 60747-1, IEC 62007-1 and IEC 62007-2.

The text of this standard is based partially on IEC 60747-5 (1992) and partially on the following documents:

FDIS	Report on voting
47C/173/FDIS	47C/186/RVD

Full information on the voting for the approval of this standard can be found in the report on voting indicated in the above table.

Annex A is for information only.

## DISCRETE SEMICONDUCTOR DEVICES AND INTEGRATED CIRCUITS –

### Part 5-3: Optoelectronic devices – Measuring methods

#### 1 Scope

This part of IEC 60747 describes the measuring methods applicable to the optoelectronic devices which are not intended to be used in the fibre optic systems or subsystems.

#### 2 Normative references

The following normative documents contain provisions which, through reference in this text, constitute provisions of this part of IEC 60747. At the time of publication, the editions indicated were valid. All normative documents are subject to revision, and parties to agreements based on this part of IEC 60747 are encouraged to investigate the possibility of applying the most recent editions of the normative documents indicated below. Members of IEC and ISO maintain registers of currently valid International Standards.

IEC 60068-1:1988, *Environmental testing – Part 1: General and guidance*

IEC 60270:1981, *Partial discharge measurements*

[SIST EN 60747-5-3:2002](https://standards.iteh.ai/catalog/standards/sist/8cdf18d0-491d-49e3-8a1b-99514830a/d/sist-en-60747-5-3-2002)

#### 3 Measuring methods for photoemitters

##### 3.1 Luminous intensity of light-emitting diodes ( $I_v$ )

###### a) Purpose

To measure the luminous intensity of semiconductor light-emitting diodes.

The method can be applied to three possible measurement variants:

###### *Variant 1*

Rotation of the diode around its mechanical axis for an accurate location of the minimum and/or maximum value.

###### *Variant 2*

Alignment of the diode optical axis with that of the optical bench.

###### *Variant 3*

Positioning according to a reference corresponding to the type of the diode envelope and allowing a reproducible mechanical orientation.

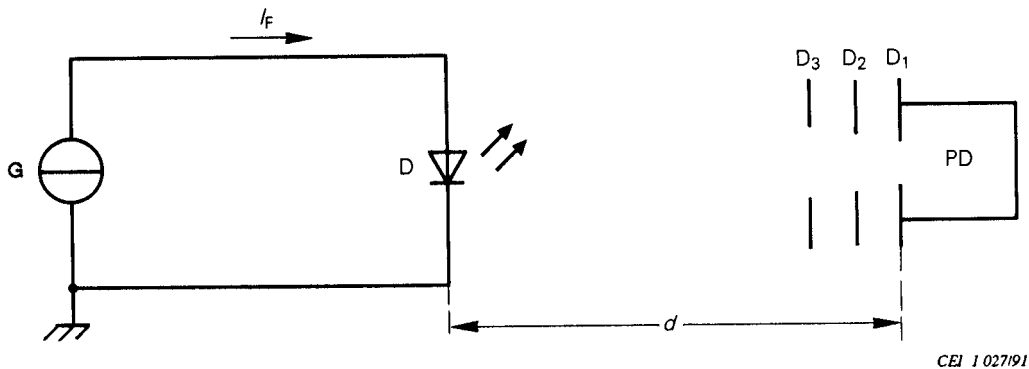
b) *Circuit diagram*

Figure 1

c) *Circuit description and requirements*

G = current source

D = light-emitting diode being measured

PD = photodetector including the diaphragm  $D_1$  of area  $A$

$D_2, D_3$  = Diaphragms intended to suppress parasitic radiations.  $D_2$  and  $D_3$  shall not limit the solid angle

$d$  = distance between the diode being measured and  $D_1$ .

The spectral sensitivity of the photometer shall be adjusted to the CIE (International Commission on Illumination) standard observers curve in the wavelength region of the light emitted by the diode. The photometer shall be calibrated in candelas at the distance  $d$ , with diaphragm  $D_1$  in place.

The distance  $d$  shall be such that the solid angle viewed by the light source at the diaphragm  $D_1$  ( $= A/d^2$ ) is less than 0,01 sr.

For pulse measurements, the current generator should provide current pulses of the required amplitude, duration and repetition rate. The photodetector should have a rise time sufficiently small in comparison with the pulse duration; it should be a peak-reading instrument.

d) *Measurement procedure*

The diode being measured is positioned according to the variant chosen.

The specified current is applied and the luminous intensity is measured on the photodetector.

e) *Specified conditions*

- Ambient temperature and, where appropriate, the atmospheric conditions.
- Forward current in the diode and, where applicable, duration and repetition rate.
- Variant: 1, 2 or 3.

### 3.2 Radiant intensity of infrared-emitting diodes ( $I_e$ )

a) *Purpose*

To measure the radiant intensity of semiconductor infrared-emitting diodes.

The method can apply to three possible measurement variants:

*Variant 1*

Rotation of the diode around its mechanical axis for an accurate location of the minimum and/or maximum value.

*Variant 2*

Alignment of the diode optical axis with that of the optical bench.

*Variant 3*

Positioning according to a reference corresponding to the type of the diode envelope and allowing a reproducible mechanical orientation.

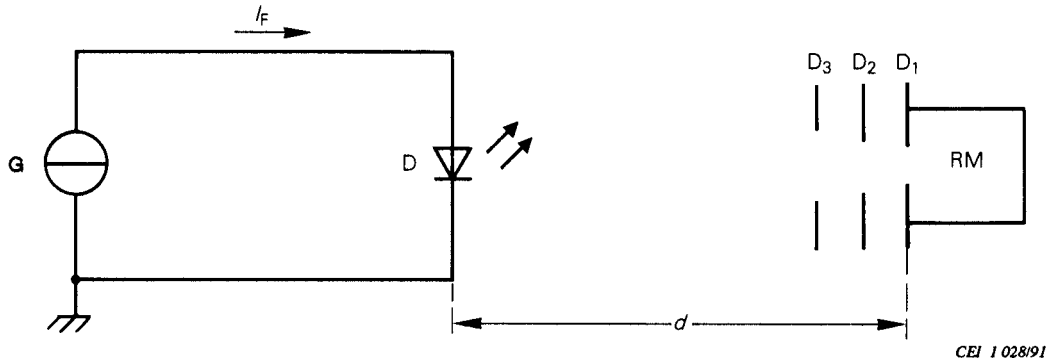
b) *Circuit diagram*

Figure 2

c) *Circuit description and requirements*

G = current source

D = infrared-emitting diode being measured

RM = radiometer including the diaphragm  $D_1$  of area  $A$

$D_2, D_3$  = diaphragms intended to suppress parasitic radiations.  $D_2$  and  $D_3$  shall not limit the solid angle

$d$  = distance between the diode being measured and  $D_1$ .

The radiant intensity  $I_e$  in the direction of the case axis should be measured by a wavelength-independent detector (for example, a thermocouple element) and the radiometer shall be calibrated in W/sr at the distance  $d$  with diaphragm  $D_1$  in place.

The distance  $d$  shall be such that the solid angle viewed by the infrared source at the diaphragm  $D_1$  ( $= A/d^2$ ) is less than 0,01 sr.

For pulse measurements, the current generator shall provide current pulses of the required amplitude, duration and repetition rate. The radiometer shall have a rise time sufficiently small in comparison with the pulse duration; it shall be a peak-reading instrument.

d) *Measurement procedure*

The diode being measured is positioned according to the variant chosen.

The specified current is applied to the diode and the radiant intensity is measured on the radiometer.

e) *Specified conditions*

- Ambient temperature and, where appropriate, the atmospheric conditions.
- Forward current in the diode and, where applicable, duration and repetition rate.
- Variant: 1, 2 or 3.